

Notice of References CitedApplication/Control No.
10/056,017Applicant(s)/Patent Under
Reexamination
NOVAK ET AL.Examiner
Zia R. HashmiArt Unit
2881

Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	T. Shigaraki, " Semiconductor Manufacturing Apparatus and Method of Manufacturing Semiconductor Devices ", Pub. No: 2002/0006675 A1, publication date: Januray 17, 2002.
	V	Y. Miwa, " Exposure Apparatus and Exposure Method", Pub. No: 2002/0071105 A1, publication date: June 13, 2002.
	W	K. Hattori et al. " Exposure Apparatus, Hol;der Container, Device manufacturing Method, and Device Manufacturing Unit ", Pub. No: 2002/0074635 A1, publication date: June 20, 2002.
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.